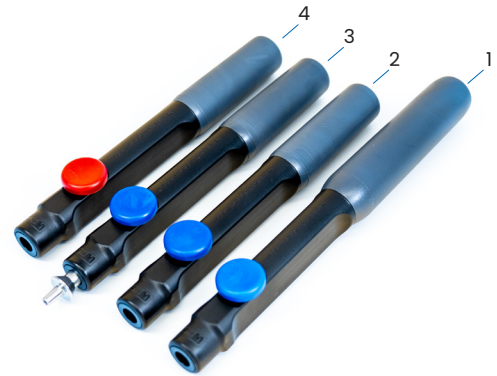


VACUUM WAND HANDLE SERIES

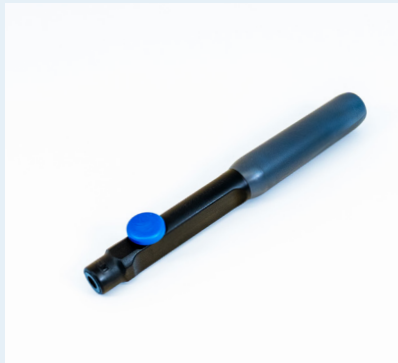
WHS offers a versatile range of ergonomic, ESD-safe handles designed for precise wafer handling in semiconductor cleanroom environments. Constructed from static dissipative polycarbonate, these handles ensure safe operation with antistatic properties, making them ideal for ISO Class 3 environments.

The WHS-V2-SM is a small grip handle, optimized for wafer handling between 50 mm and 150 mm. Its compact size and lightweight design offer enhanced control during smaller substrate handling operations. The WHS-V2-LG is the large grip handle, designed for handling larger wafers between 150mm and 300 mm, providing added comfort and stability for heavier weight substrates.

All WHS-V2 wand handles are precision-molded, which enhances cleanliness, repeatability, and product



1. WHS-V2-LG | 2. WHS-V2-SM | 3. WHS-V2-SD |
4. WHS-V2-SMNC



consistency. Special ergonomic engineers have further enhanced the hand comfort and feel of these products, providing a significant improvement over previous market options.

For special applications, the WHS-V2-SD model builds upon the small grip design of the WHS-V2-SM and includes the WHS-V5-SD small device adapter, making it the ideal choice for users handling small components such as die, optics, or packages. The WHS-V2-SMNC is a normally closed vacuum wand handle, specially designed for closed-valve systems. It features a red button for quick identification, while the normally open wand handles are equipped with blue buttons to differentiate between the two.

All WHS-V2 handles feature a universal press-fit design, compatible with WHS vacuum tips from 50 mm to

300mm. Engineered with an anti-crimp hose barb, these handles are robust and durable, providing long-lasting reliability while minimizing vacuum cord wear.

WHS-V2 vacuum wand handles are manufactured in an ISO9001-certified facility and CE-certified, ensuring the highest quality and performance standards for semiconductor wafer handling.

FEATURES AND ADVANTAGES

- Precision-molded for cleanliness and consistency
- ESD-safe polycarbonate for ISO Class 3 cleanrooms
- WHS-V2-SM: Small grip, 50mm to 150mm wafers
- WHS-V2-LG: Large grip, 150mm to 300mm wafers
- Anti-crimping cord mounting feature

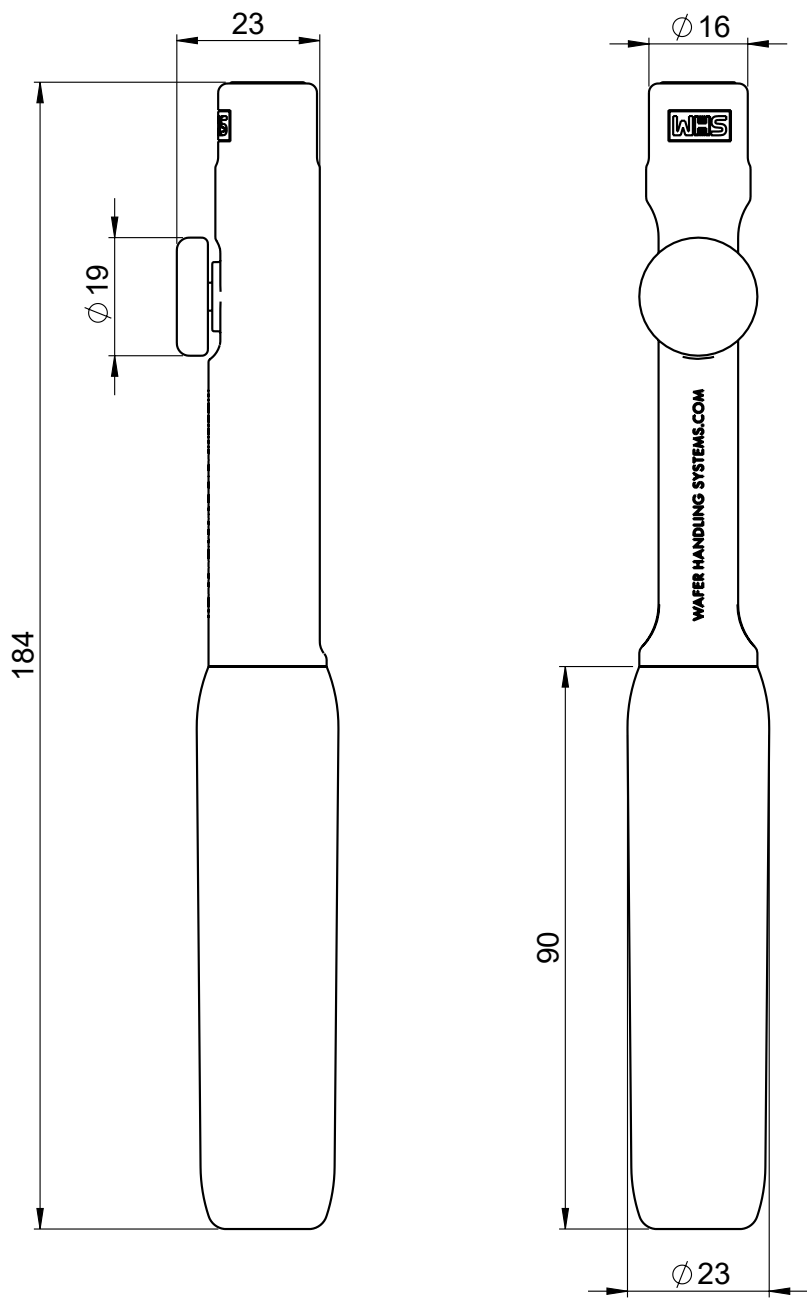
VACUUM WAND HANDLE SERIES

ITEM	SPECIFICATIONS
Style, standard	Press fit, normally open
Material, body	Antistatic polycarbonate
Material, handle	Antistatic polycarbonate
Material, button	Antistatic polycarbonate
Cleanliness	ISO 3 (Class 1 FS209E)



ORDERING INFORMATION

WHS-V2-	LG
CODE	MODEL
LG	Vacuum wand handle, normally open, pressfit, antistatic, large grip (1)
SM	Vacuum wand handle, normally open, pressfit, antistatic, small grip (2)
SD	Vacuum wand handle, normally open, pressfit, antistatic, small grip for small devices (3)
SMNC	Vacuum wand handle, normally closed , pressfit, antistatic, small grip (4) (Red button)



Materials:
Handle: Antistatic Polycarbonate
Body: Antistatic Polycarbonate
Button: Antistatic Polycarbonate

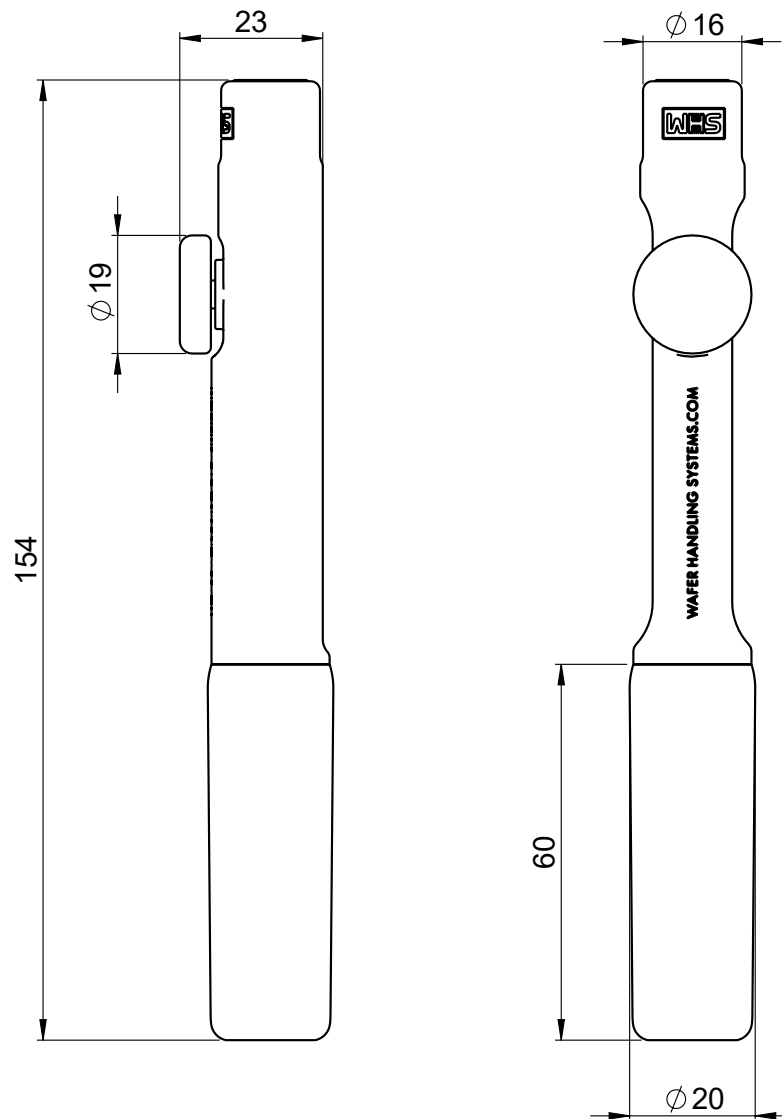


WHS-V2-LG

Vacuum Wand Handle, N.O. Pressfit, Antistatic, Large Grip

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**Materials:**

Handle: Antistatic Polycarbonate

Body: Antistatic Polycarbonate

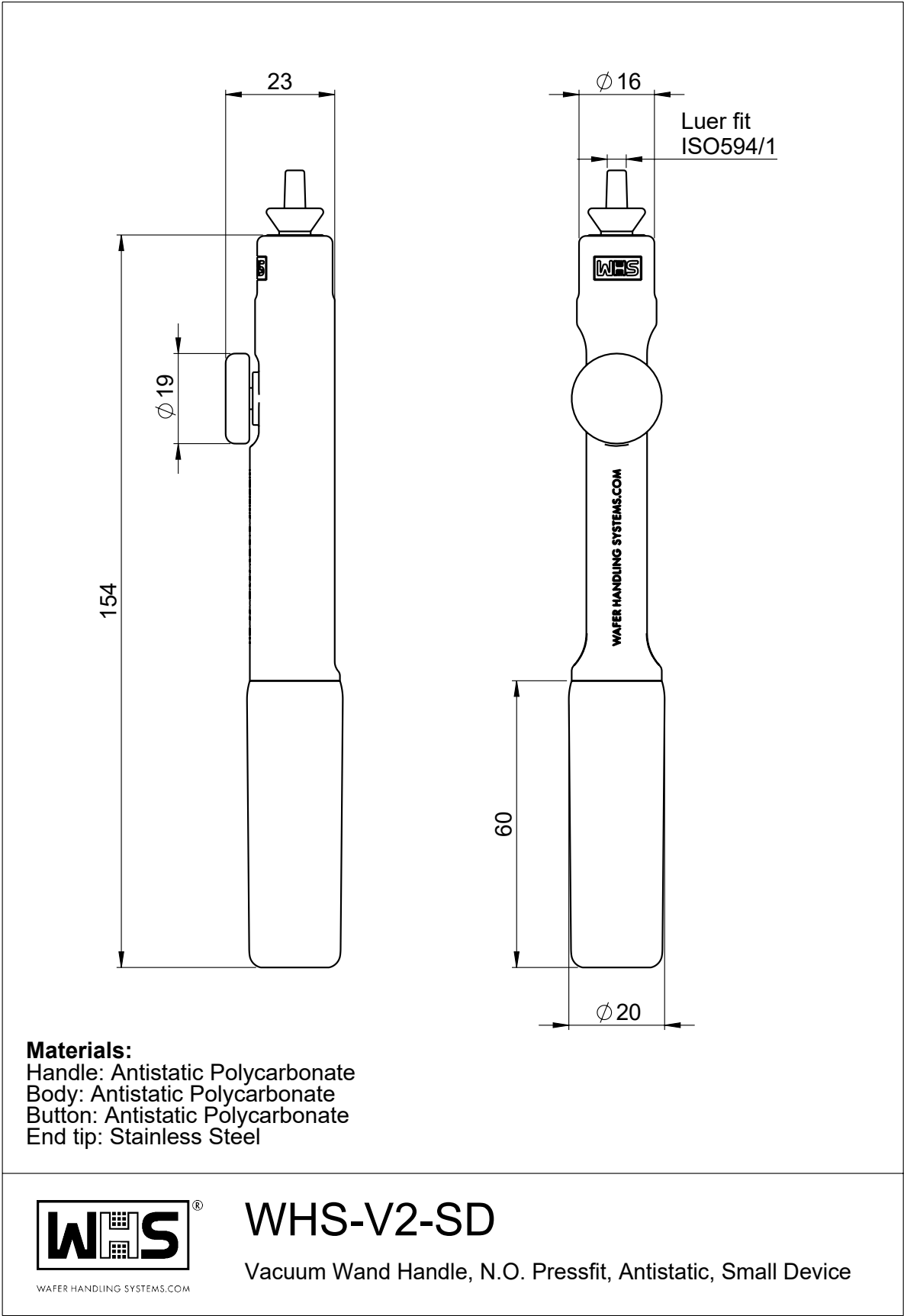
Button: Antistatic Polycarbonate

**WHS-V2-SM**

Vacuum Wand Handle, N.O. Pressfit, Antistatic, Small Grip

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